

UNITED STATES PATENT AND TRADEMARK OFFICE

Examiner:.

Group:

Attorney Docket # 3220

Applicant(s): OESTERSCHULZE, E., ET AL

Serial No.:

Filed:

For : METHOD FOR PRODUCING AT LEAST ONE SMALL  
OPENING IN A LAYER...

**INFORMATION DISCLOSURE STATEMENT**

February 1, 2005

Honorable Commissioner of Patents  
and Trademarks  
Washington, D.C. 20231

S I R S:

X  In accordance with the Duty of Disclosure, Applicant(s) submit(s) herewith a copy of a Foreign Search Report in a counterpart application and copies of the reference(s) indicated therein.

X  In the event that the Foreign Search Report is in a foreign language, a translation thereof is herewith submitted.


X  Attached hereto is a FORM PTO 1449 listing the references.

X  Attached hereto is a copy of a reference cited in the specification of the application as filed. The specification itself recites the relevance of these documents, and pursuant to M.P.E.P. Section 609 A (3) this represents an acceptable Statement of Relevancy. The reference(s) appear(s) at the following page(s) and line(s) of the specification: page 1 line 32, page 2 line 10, page 5 line 32, page 8 line 19, page 11 line 32, page 12 lines 17-18, page 13 lines 8-9, page 15 line 20.

Applicant petitions for consideration of this Information Disclosure Statement since it is being submitted after receipt of an office action. It is respectfully requested that the required fee be charged to the account of the undersigned: 19-4675.

- \_\_\_ Attached hereto are copies of references cited which may be pertinent to this application. Since the references are in the English language, no statement of relevancy is submitted.
- \_\_\_ Attached hereto is a copy of the Office Action issued in the corresponding German and European applications, together with a translation thereof and copies of the references cited therein. A list of the cited references is also attached.
- \_\_\_ Attached hereto copies of references cited which may be pertinent to this application. An English translation of the reference is also attached.
- \_\_\_ Attached hereto is a Statement of Relevancy and copies of references cited therein.
- \_\_\_ Relevancy is indicated in an English language abstract or an English language equivalent attached hereto.

Respectfully submitted,

  
Michael J. Striker  
Attorney for Applicant(s)  
Reg. No. 27233

# INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

ATTY DOCKET NO.

3220

APPLICATION NO.

107523468

APPLICANT(S)

OESTERSCHULZE, E., ET AL

1 Rec'd PCT/PT

01 FEB 2005

FILING DATE

GROUP ART UNIT

## U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	6,794,296 B1	09/21/2004	KASSING ET AL			
	5,501,893	03/26/1996	LAERMER ET AL			
	5,272,913	12/28/1993	TODA ET AL			
	5,116,462	03/26/1992	BARTHA ET AL			
	5,399,232	03/21/1995	ALBRECHT ET AL			

## U.S. PATENT APPLICATION PUBLICATIONS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

## FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
	199 26 601 A1	03/23/2000	DE			✓	
	42 41 045 C1	05/26/1994	DE			✓	
	41 26 151 A1	03/05/1992	DE			✓	
	42 02 447 A1	07/30/1992	DE (ENGLISH ABSTRACT)			✓	

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

		OLSCHMIKE ET AL: "FABRICATION OF 15 MUM THICK..." MICROELECTRIC ENGINEERING, ELSEVIER PUBLISHERS BV., AMSTERDAM NL, BD. 6, MR. 1-4, DECEMBER 1987, PP. 547-552.
		LAERME, F., ET AL: "BOSCH DEEP SILICON ETCHING..." TECHNICAL DIGEST, IEEE INTERNATIONAL MEMS 99 CONFERENCE, TWELTHS IEEE INTERNATIONAL CONFERENCE ON MICRO ELECTRO MECHANICAL SYSTEMS, IEEE PISCATAWAY, NJ, USA, JANUARY 17, 1999 - JANUARY 21, 1999, PP. 211-216.

EXAMINER

DATE CONSIDERED

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

**INFORMATION DISCLOSURE CITATION**  
(Use several sheets if necessary)

ATTY DOCKET NO.

3220 DT01

Rec'd PCI/PT

APPLICATION NO. 10/0523468  
01 FEB 2005

APPLICANT(S)  
OESTERSCHULZE, E., ET AL

FILING DATE

GROUP ART UNIT

**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	5,770,465	06/23/1998	MACDONALD ET AL			
	6,156,215	12/05/2000	SHIMADA ET AL			

**U.S. PATENT APPLICATION PUBLICATIONS**

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

**FOREIGN PATENT DOCUMENTS**

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

		GEORGIEV, G., ET AL: "LITHOGRAPHY-FREE FABRICATION OF..." JOURNAL OF VACUUM SCIENCE & TECHNOLOGY B: MICROELECTRONICS PROCESSING AND PHENOMENA, AMERICAN VACUUM SOCIETY, NEW YORK, NY US, BD. 21, NR. 4, JULY 4, 2003, PP. 1361-1363.

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